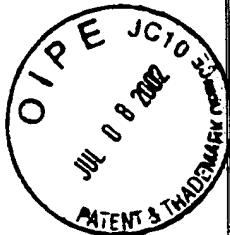


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

894  
07/19/02  
#6A

Applicant(s): Yoo, Woo Sik  
Assignee: WaferMasters, Inc.  
Title: Wafer Transport System and Method  
Serial No.: 09/838,083 Filing Date: April 19, 2001  
Examiner: Charles A. Fox Group Art Unit: 3652  
Docket No.: M-11439 US

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RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action dated March 28, 2002, Applicants submit the following amendments and remarks.

IN THE CLAIMS

The following is a clean version of the entire set of pending claims. No Claims are amended.

1. A method for transporting semiconductor wafers comprising:  
providing a processing system including a transport module and process chamber;  
extending a semiconductor wafer transport device from said transport module into an adjacently positioned container, said container being a separate component from said processing system; and  
removing at least one semiconductor wafer from said container using said wafer transport device.

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